

InGaN Quantum Dots for Room Temperature Single Photon Sources

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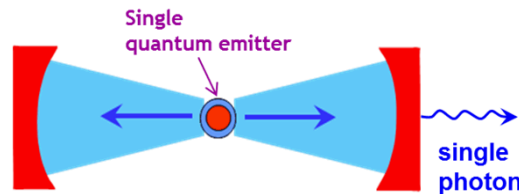
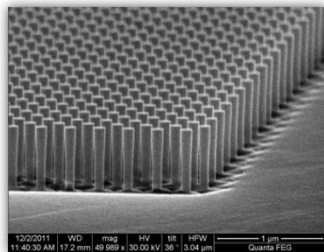
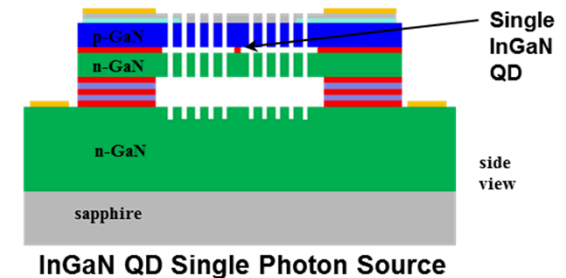
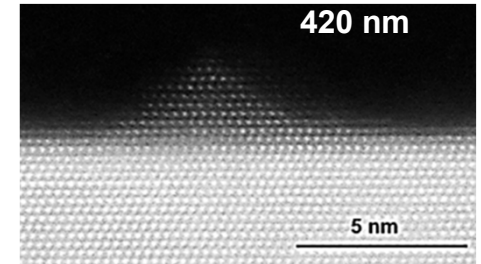
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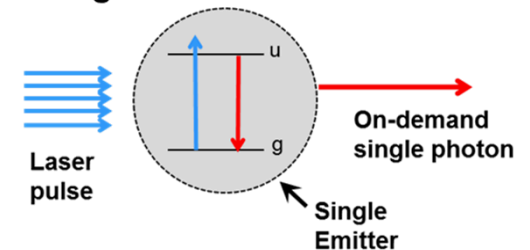
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Outline:

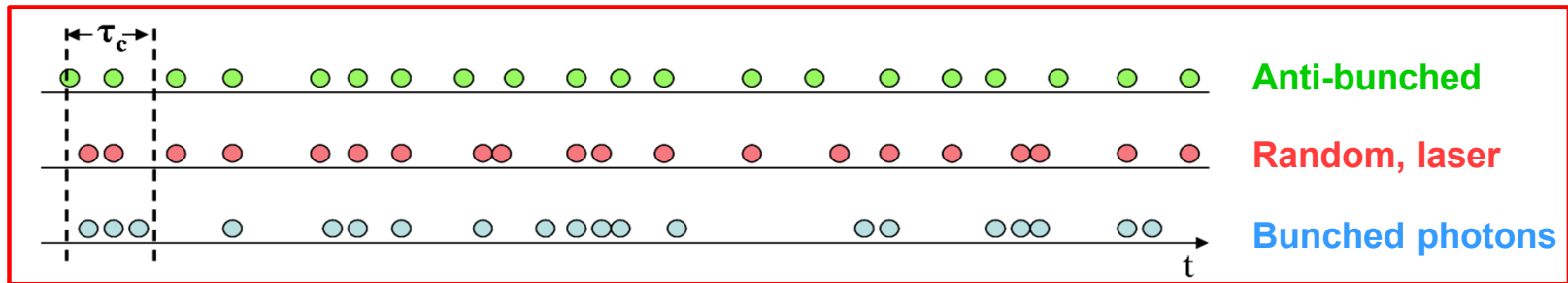
1. Motivation: QD single photon sources
2. InGaN QD fabrication
 - Quantum size controlled PEC etching
3. AFM/TEM analysis of InGaN QDs
4. Optical characterization of QDs
 - Photoluminescence, TRPL
5. Deterministic placement of InGaN QDs
 - Emission from single InGaN QDs
 - Photonic crystal based single photon source
6. Calculated g^2 for multi-dot systems
 - Studying the transition from classical to quantum
7. Summary/Conclusions



Single Quantum Emitter



Single Photon Source: Photon Statistics



source: J.S. Lundeen

Classical light sources: $g(2)(t = 0) \geq 1$

- Bunched or random photons (Laser, LED, thermal source)

Quantum light source: $g(2)(t = 0) < 1$

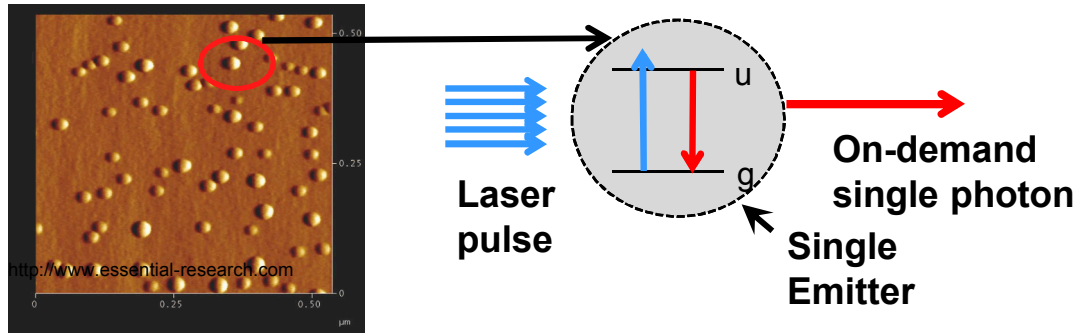
- Anti-bunched photons (Quantum optics theoretical treatment)

Applications:

- **Quantum key distribution**
 - Attenuated laser can be used
 - SPS is the gold standard for QKD
 - Future QKD involving quantum repeaters
- Quantum metrology
- Quantum computing with photons
- True random number generation

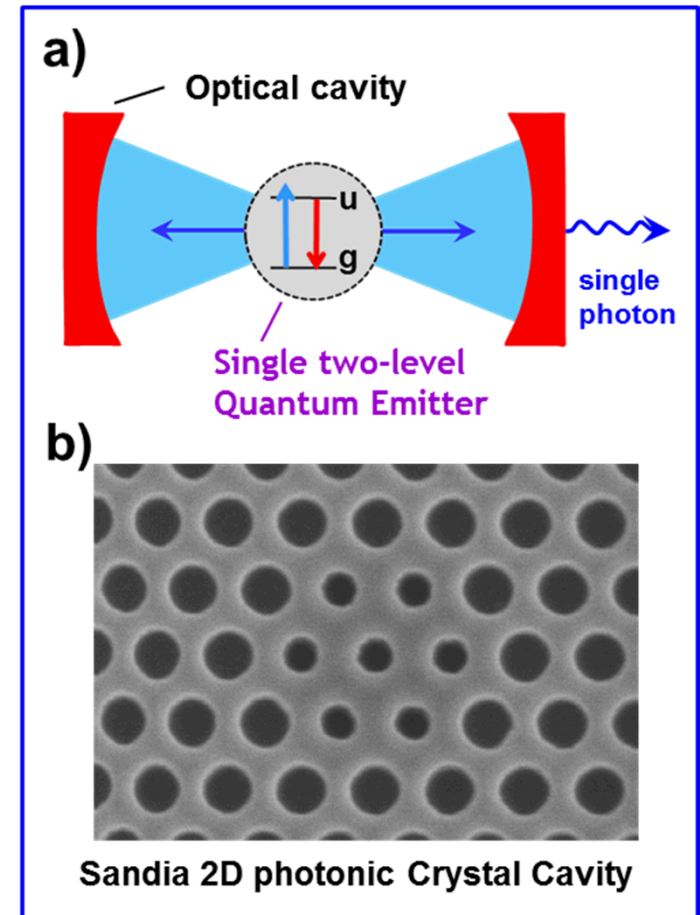
Single Photon Source based on Quantum Dots

AFM image of InAs QDs



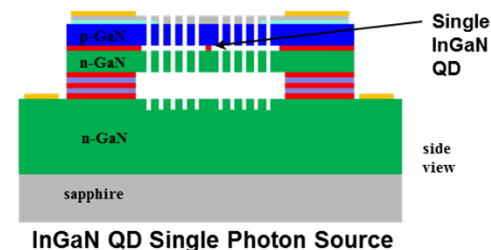
QD Single Photon Source:

- Isolate emission from a single quantum dot
- Only one photon can be emitted
 - Absorption of one photon saturates transition
 - Can be excited using many photons
 - **Deterministic Source: on demand**
- Triggered emission within radiative lifetime
 - Short emitter lifetime (~ 1 ns) \rightarrow Fast rep. rate
- **Path to electrical-injection/chip-scale integration**

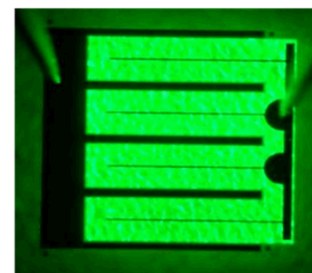


InGaN Quantum Dot SPS Development

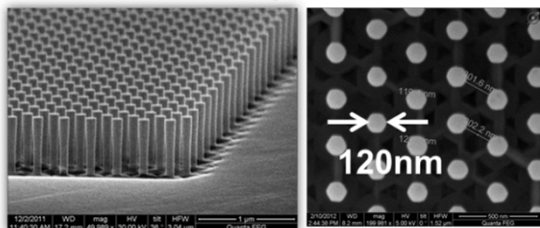
- **Goal:** Room temperature, electrically-injected, chip-scale single photon source
- Our approach:
 - Develop a III-nitride QD capability at Sandia
 - **MOCVD-grown InGaN QWs → PEC etched InGaN QDs**
 - **Design a PhC cavity for InGaN QD SPSs**
- Advantages to this approach
 - **InGaN QDs can operate at high temperatures**
 - **Deterministic placement of InGaN QDs**
 - Leverage previous work in III-nitride optoelectronics
 - Leverage SNL PhC design, fabrication expertise



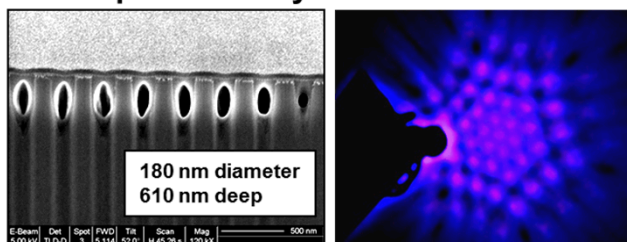
Green InGaN LEDs



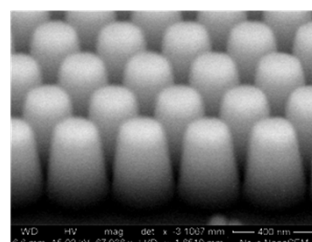
GaN nanowire arrays



InGaN photonic crystal LEDs



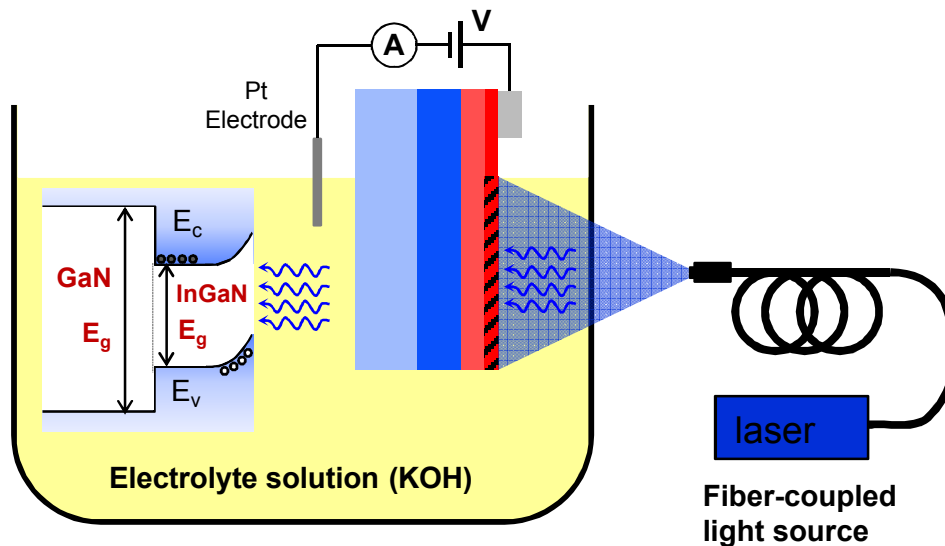
InGaN nano-LED array



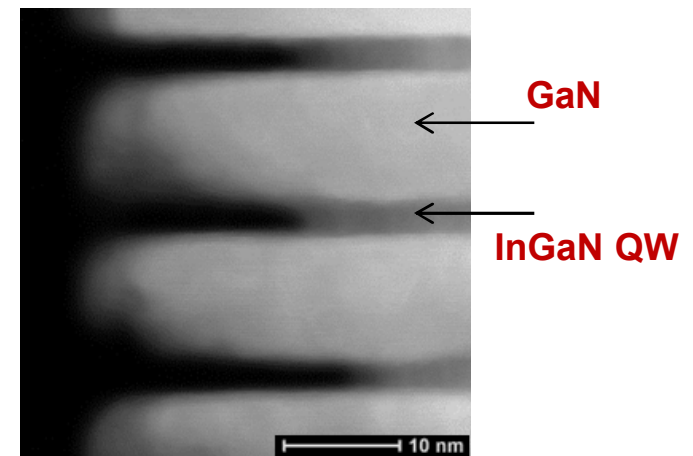
Introduction to InGaN PEC Etching

Photoelectrochemical (PEC) Etching:

- Very few wet etches work for III-nitrides
- **Band gap selective (Etch InGaN over GaN)**
- Dopant selective, light intensity dependent, etch current can be monitored
- Laser or lamp excitation (Xe arc lamp, tunable ps Ti:S)
- KOH ($\sim 0.1\text{M}$) typically used as electrolyte



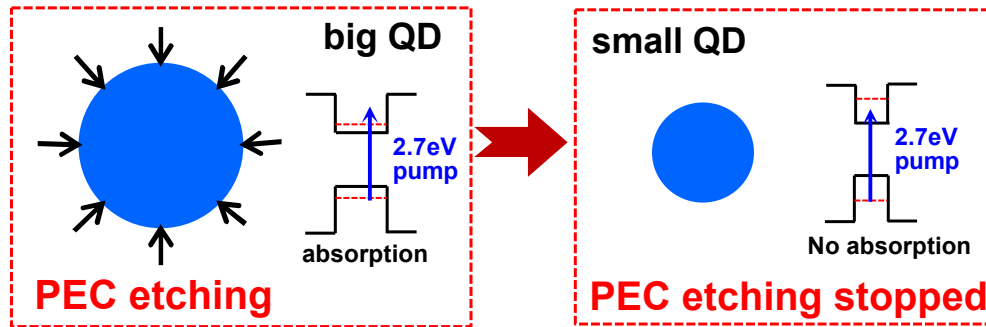
PEC etched InGaN/GaN QWS



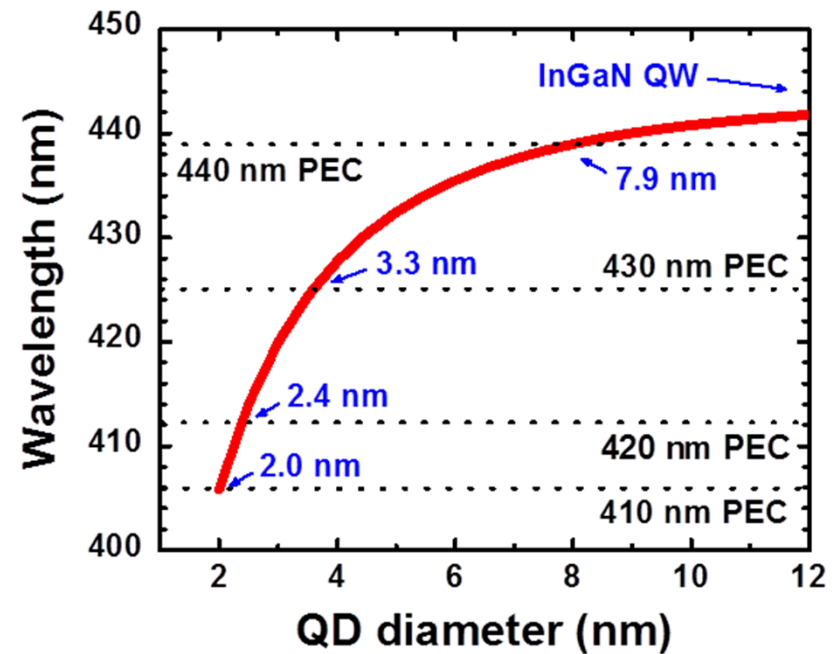
Fabrication of InGaN QDs via PEC etching

Quantum Size Control: Use size quantization to control QD size

Self-limiting PEC etch process:



- For QDs, band gap depends on size
- As etch proceeds,
 - QD size gets smaller, band gap goes up
 - Etch terminated for $E_g > E_{\text{photon pump}}$
- **Self-terminating etch process**
- **QD size depends on PEC wavelength**
- **Monodisperse QD distributions ??**



G. Pellegrini, et al., Journal of Applied Physics 97, 073706 (2005).

MOCVD-grown InGaN samples

Uncapped single InGaN QW



- Grown by MOCVD on sapphire substrates
 - 5 - 20 nm thick InGaN layer
- No InGaN underlayer is used in this sample
- Uncapped single QW sample (14% In):
 - Amenable to surface characterization of QDs
 - TEM, AFM characterization
 - Luminescence weaker than capped sample

Capped single InGaN QW



- Grown by MOCVD on sapphire substrates
 - 3 nm InGaN QW, 10 nm GaN cap
- InGaN underlayer (~2% In) used in this sample
- Capped single QW sample (14% In):
 - AFM is not useful for capped samples
 - Luminescence brighter than uncapped samples
- Etch is thought to proceed via pits, dislocations

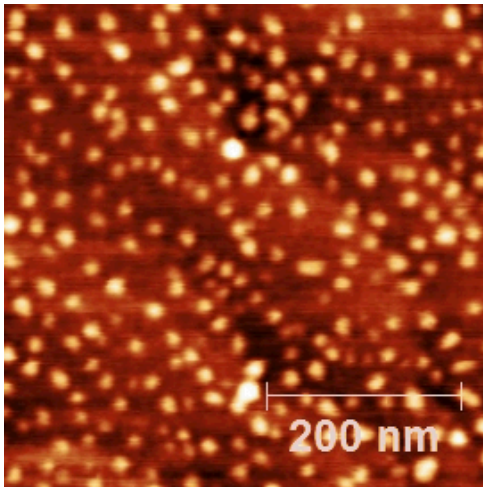
Atomic Force Microscope (AFM) Measurements

Uncapped InGaN QW

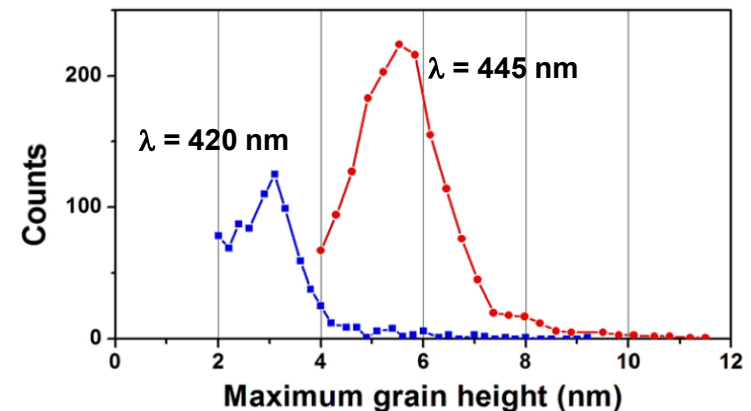
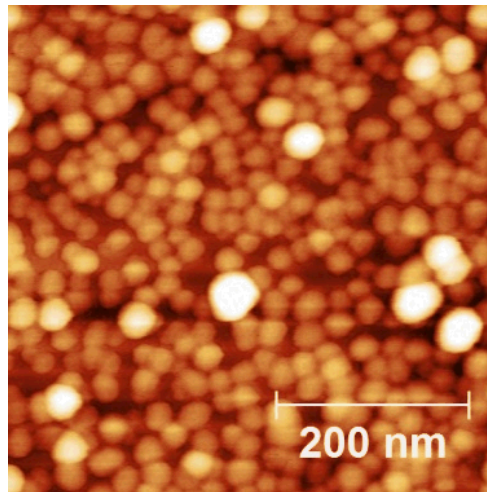


- Samples etched for two hours at 420 nm and 445 nm
 - Laser power density: $\sim 3 \text{ mW/cm}^2$
- High dot density: $10^{11}/\text{cm}^2$
- Some big dots (10-20 nm) remain: due to dislocations?
- QD size depends on PEC etch wavelength

PEC etch $\rightarrow \lambda = 420 \text{ nm}$



PEC etch $\rightarrow \lambda = 445 \text{ nm}$

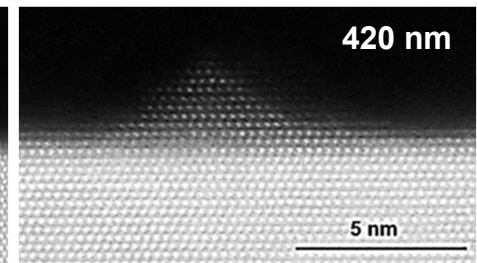
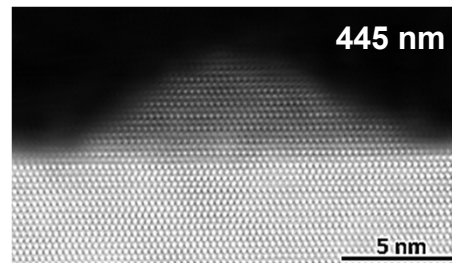
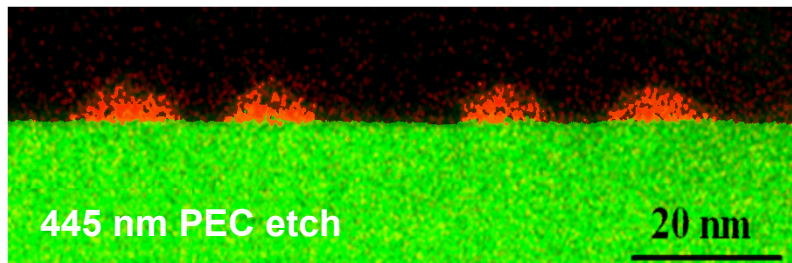
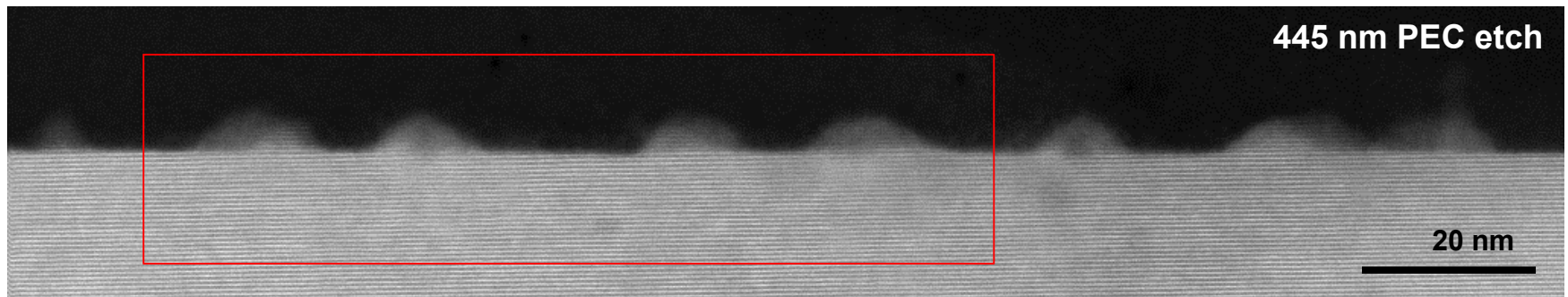


Transmission Electron Microscope (TEM) Images

Uncapped InGaN QW



- High-angle annular dark-field (HAADF) TEM images
- Samples etched at 420 nm and 445 nm
- Energy dispersive x-ray mapping
 - QDs on surface are InGaN
 - Red = indium, green=gallium
- InGaN QDs are epitaxial to the underlying GaN
- No underlayer, no cap → PL is not very bright



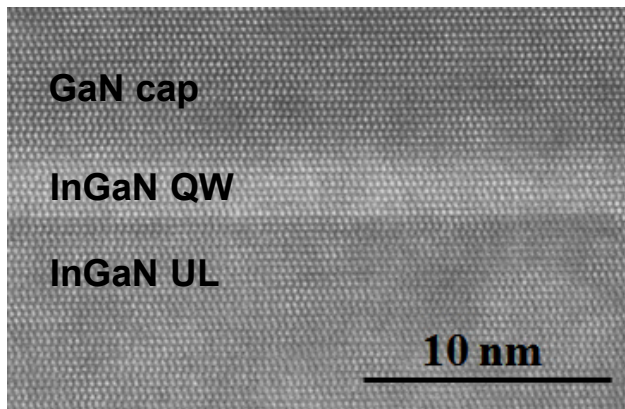
Transmission Electron Microscope Images

Capped InGaN QW

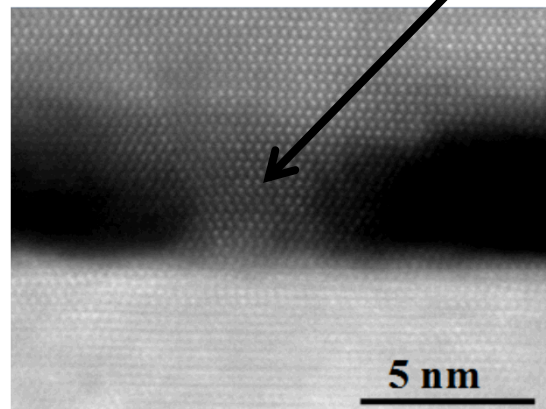


- High-angle annular dark-field (HAADF) TEM images
- Sample etched at 420 nm
- EDX mapping shows that dots are InGaN
- InGaN QDs are epitaxial to the underlying GaN
- 2% InGaN underlayer + GaN cap → PL is much brighter
- GaN cap provides partial passivation

before PEC etch

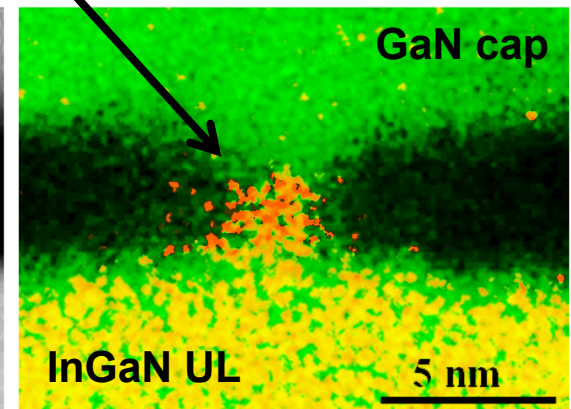


after PEC etch



InGaN QD

after PEC etch



Photoluminescence from fabricated InGaN QDs

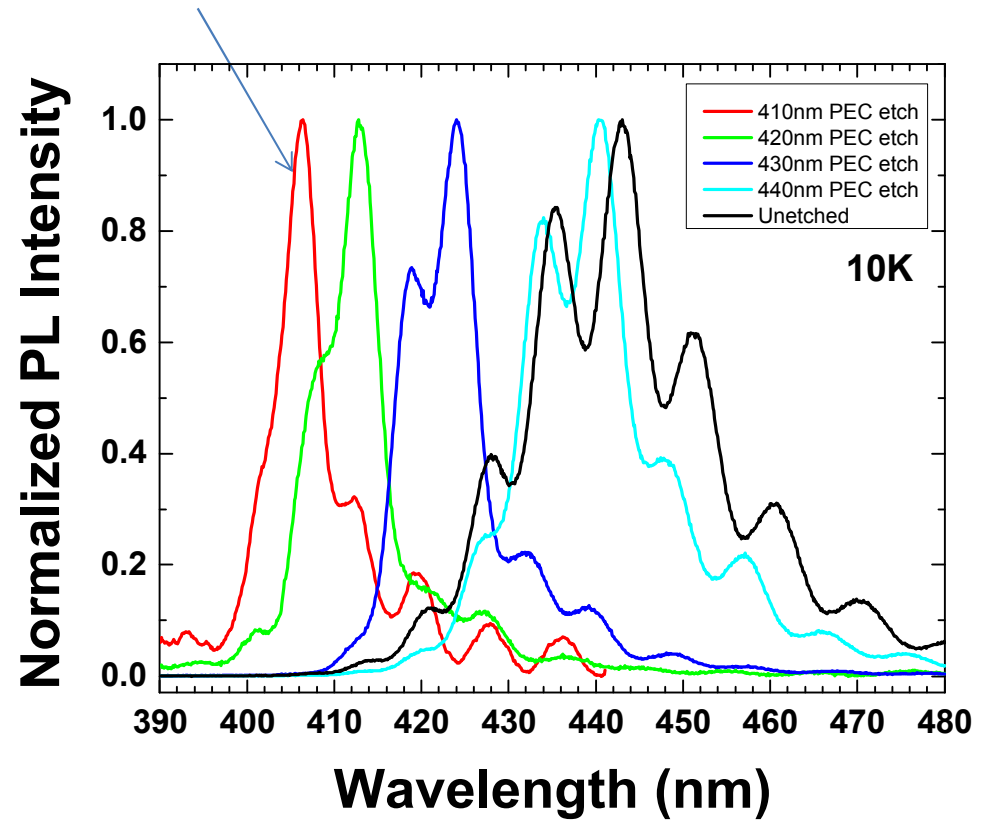
Capped InGaN QW

GaN cap
InGaN QW
InGaN underlayer
n-GaN
Sapphire

Photoluminescence (PL) data:

- 375 nm pump (ps pulsed)
- 10K PL data
- PL wavelength determined by PEC etch wavelength
- PL linewidth: 24 nm \rightarrow 6 nm
- **Quantum size-controlled PEC etching works!**

As narrow as **6 nm** FWHM is consistent with a narrowing of the QD size distribution

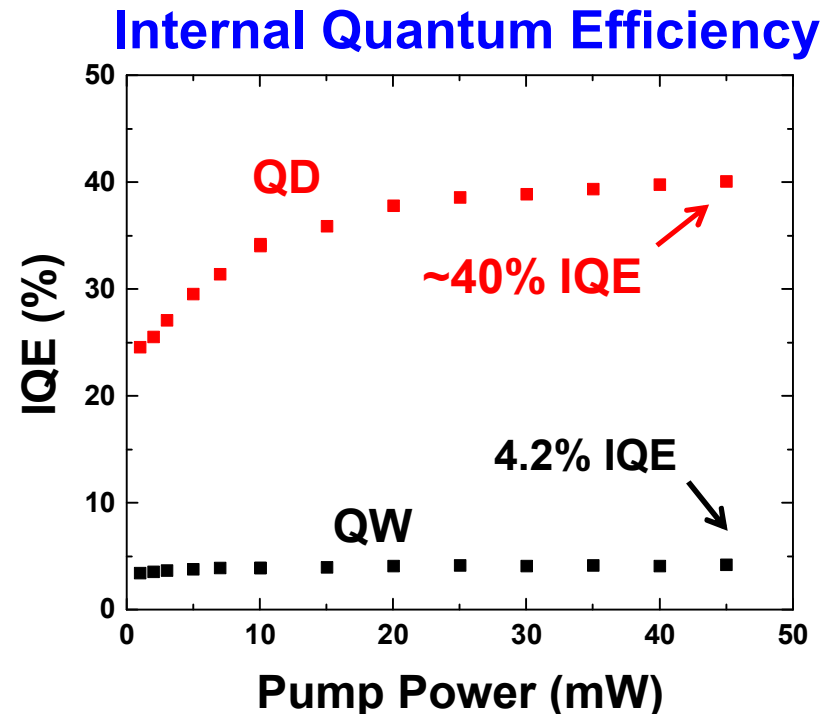
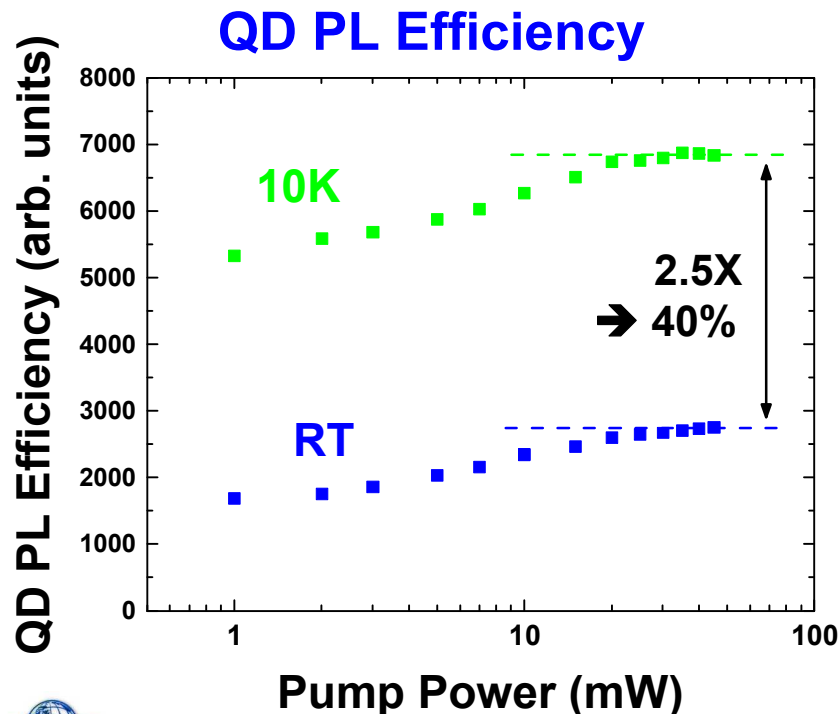


InGaN QD internal quantum efficiency

Capped InGaN QW

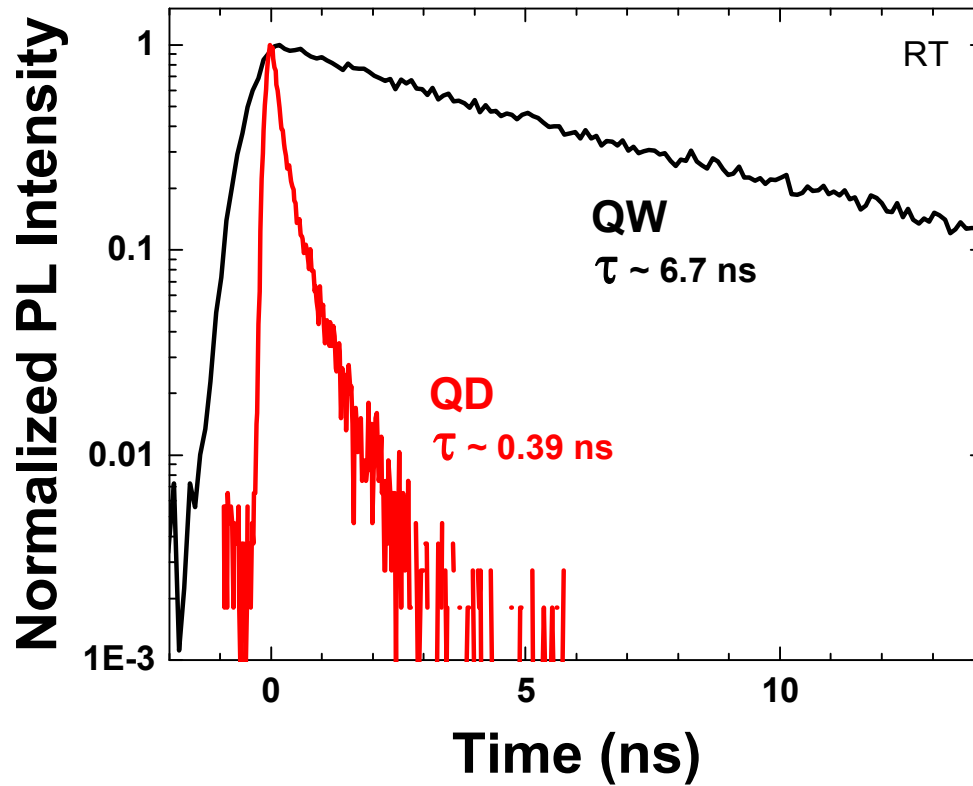


- Compare 10K and RT PL efficiency
- Assumes 10K PL is 100% efficient
- PL Intensity drops by >100X after QD etching
- IQE goes up by almost 10X after QD etching
- QDs are expected to have better IQE



Time-resolved PL data from InGaN QDs

Capped InGaN QW



TRPL data:

- 405 nm pump (~ 2 ps, pulsed)
- Resonant pumping into InGaN
- Room temperature TRPL data
- Hamamatsu streak camera data
- 17X change in PL lifetime
- Lifetime is expected to be much shorter for QDs
- Shows that we have fundamentally changed the InGaN material
- QW \rightarrow QDs

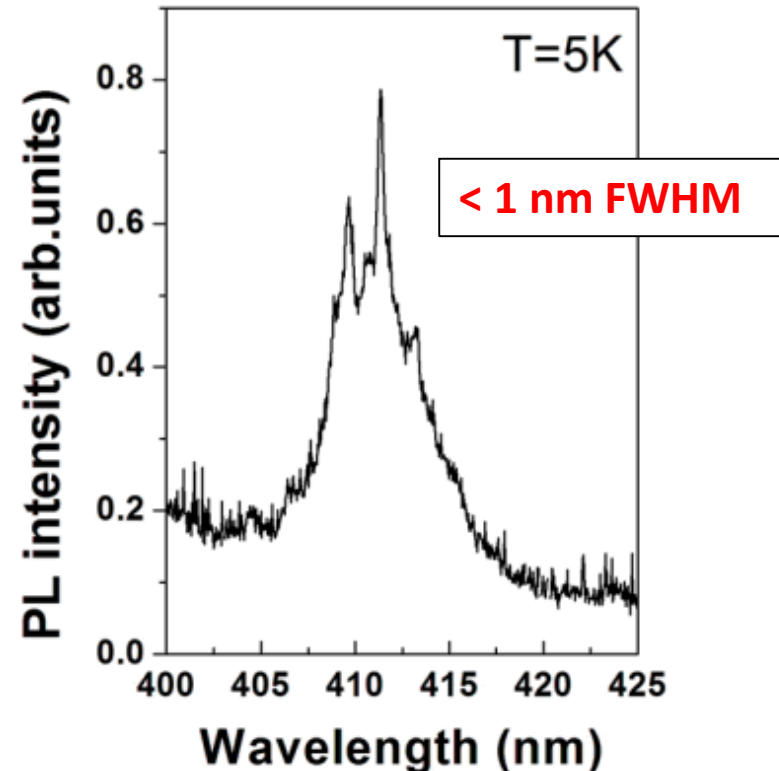
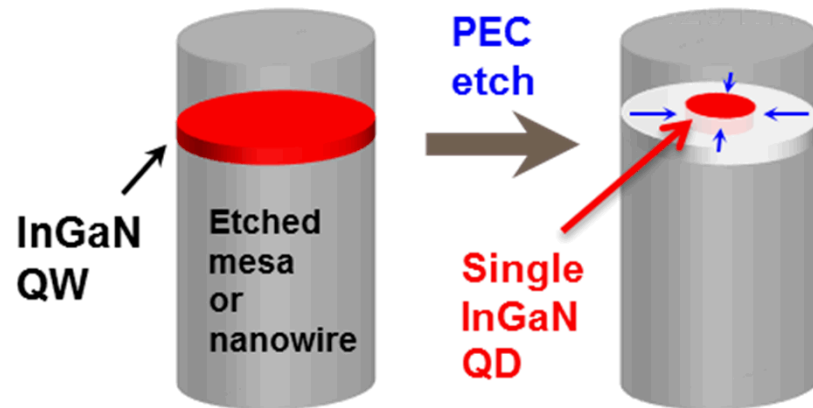
Emission from single InGaN QDs

Capped InGaN QW



- Posts (150 – 200 nm) patterned with e-beam lithography
- Narrow PL emission (<1 nm FWHM) observed
- Fabricate InGaN QDs at deterministic locations
- InGaN QD single photon source

Fabrication of single InGaN QDs



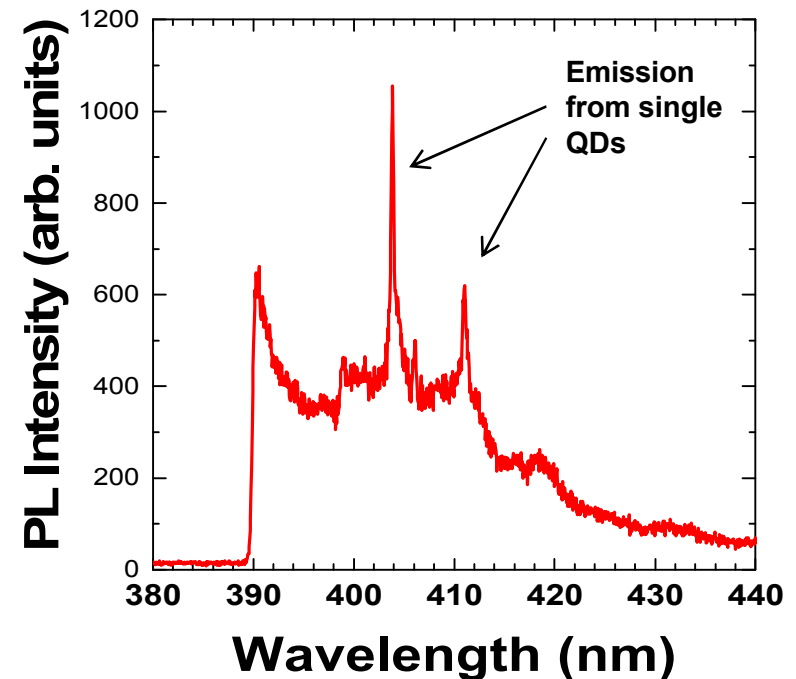
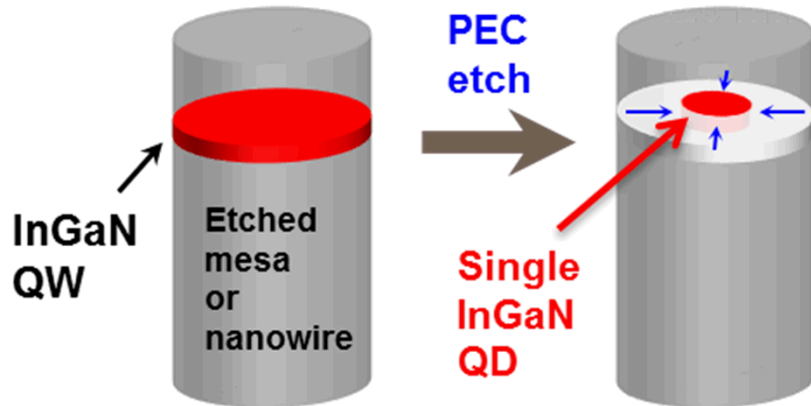
PL from InGaN QDs (newer data)

Capped InGaN QW

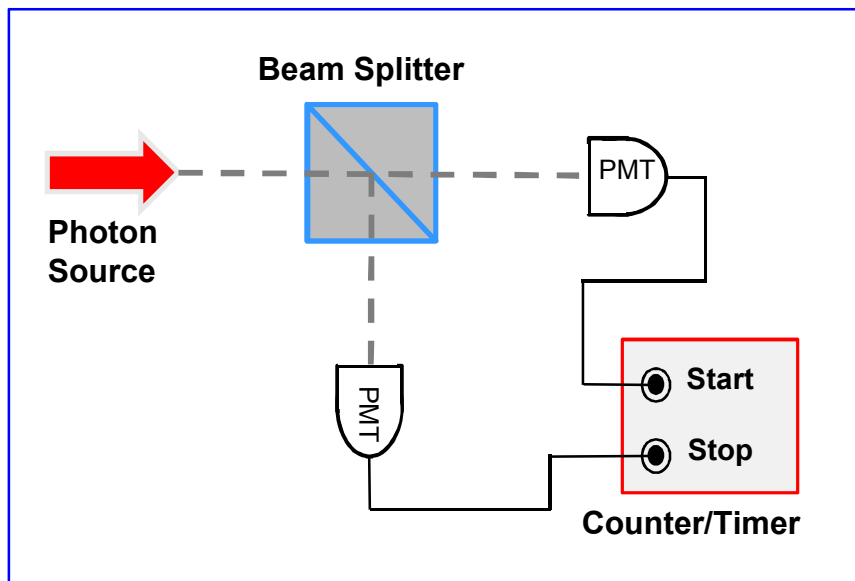
GaN cap
InGaN QW
InGaN underlayer
n-GaN
Sapphire

- Posts (150 – 200 nm) patterned with e-beam lithography
- Thicker GaN capping layer (~ 30 nm)
- Narrow PL emission (<1 nm FWHM) observed
- Better ratio of single QD mission to background
- Limited by motion of closed-cycle cryostat

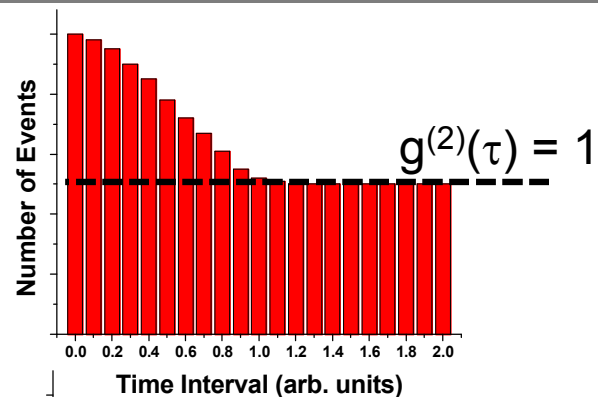
Fabrication of single InGaN QDs



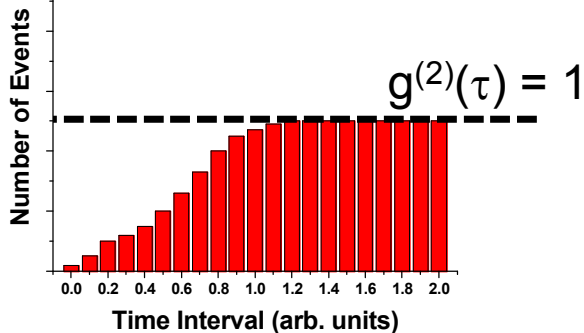
Single Photon Measurement: HBT experiment



Thermal Source
 $g^{(2)}(0) > 1$



Quantum Source
 $g^{(2)}(0) < 1$

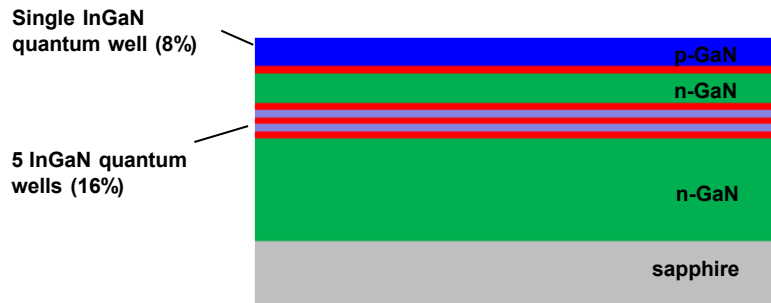


- Non-polarizing beamsplitter to split intensity between detectors
- Single photon counting required
 - Use PMTs or avalanche photodiodes
 - Single photon counting modules
- Measure correlation between detected photons
- Detectors: low QE, speed, and dark counts

Deterministically Positioned InGaN QDs

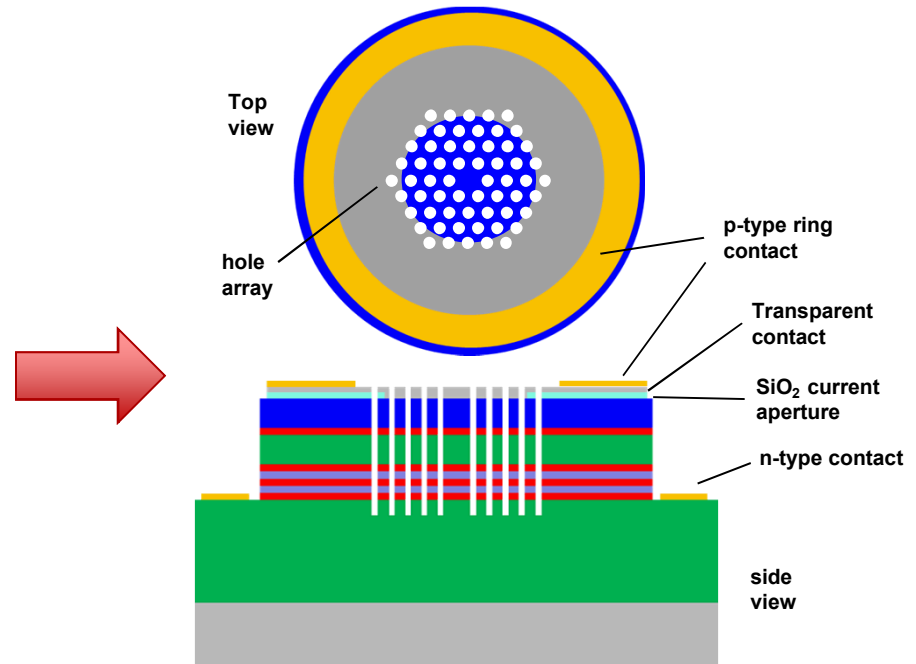
Standard III-nitride device fabrication

1.) Epitaxial layer structure



- Specially design epitaxial structure for PEC etching
- InGaN QWs with 8% and 16% indium

2.) Fabrication of device plus PhC etch

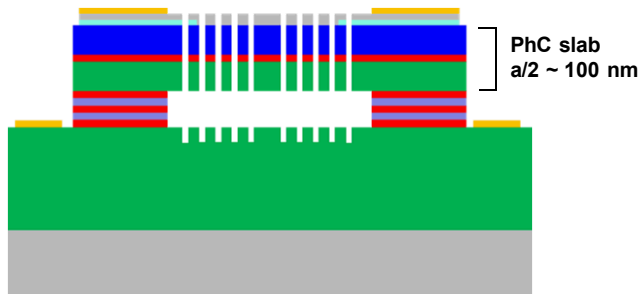


- Standard LED fabrication
- Etch PhC triangular array
- defect cavity at the center
- Requires current aperture
- Use transparent contact

Deterministically Positioned InGaN QDs

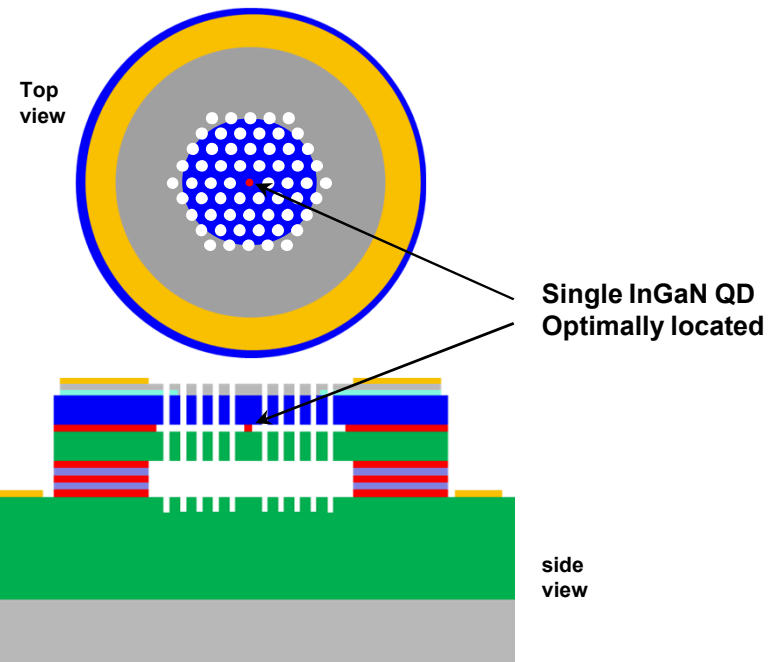
PEC etch of InGaN QWs

3.) First photoelectrochemical etch



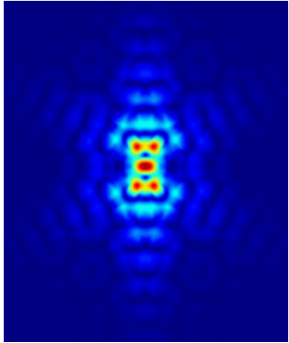
- Use 450 nm laser for PEC etch
- Area under contacts will not etch
- 8% InGaN QW will not etch

4.) Second photoelectrochemical etch

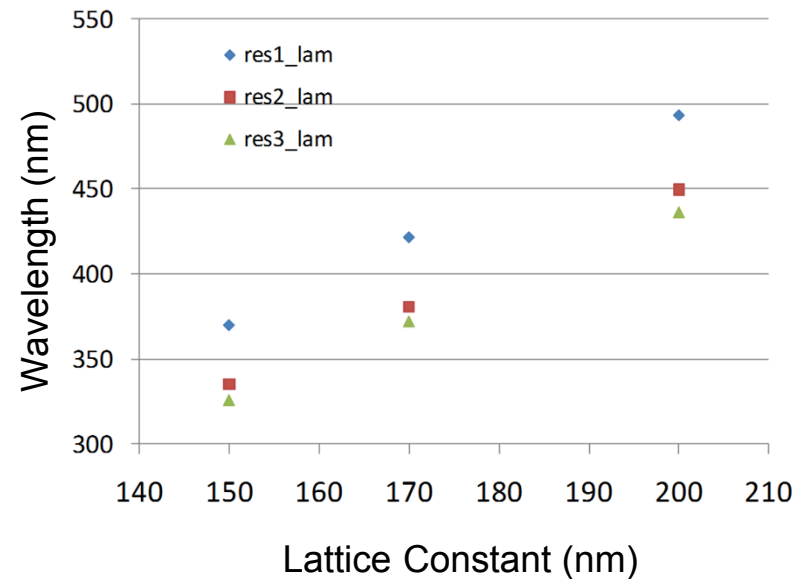
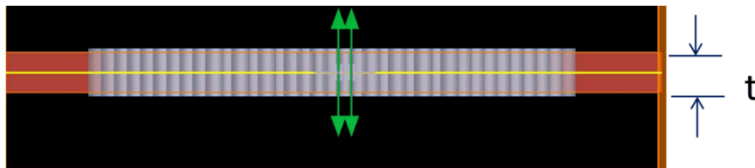
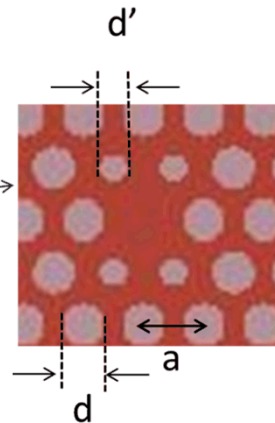
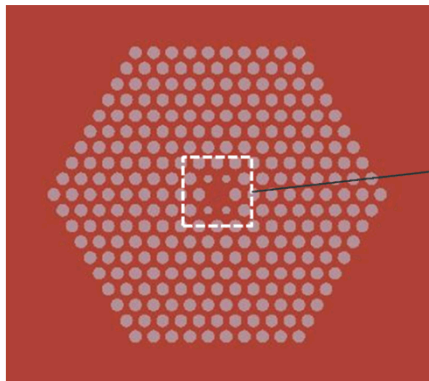


- Use 405 nm laser for PEC etch
- Self limiting PEC etch
- Size quantization in QD will raise energy level above 405 nm

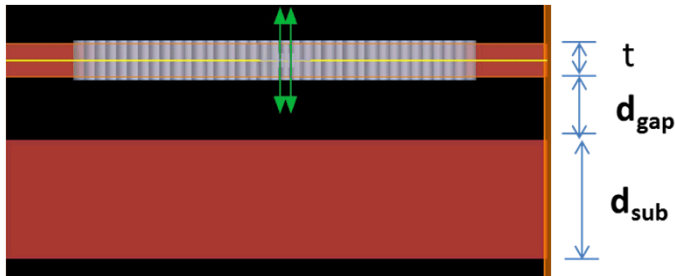
FDTD Photonic Crystal Modeling



- Calculations done using Lumerical
- Need resonance with anti-node at center (res1)
- Calculated cavity Q is 941 for this design (no substrate)
- Design is not fully optimized (higher Qs are possible)
- Need lattice constant in the range from 170 – 200 nm

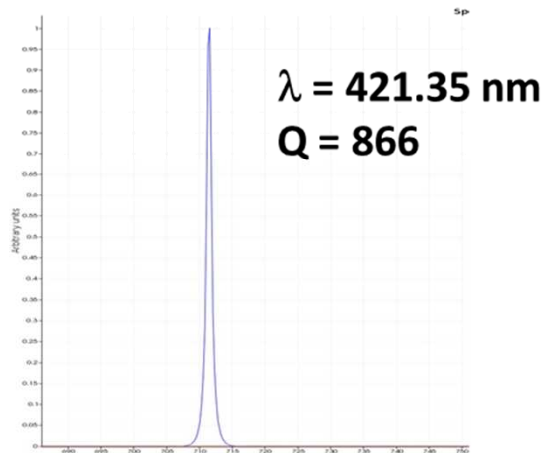


FDTD Modeling: Spacer Layer Thickness



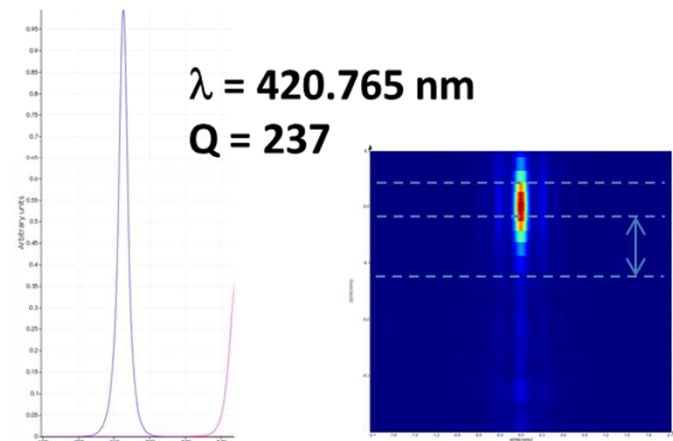
- High-angle annular dark-field (HAADF) TEM
- Sample etched at 420 nm
- EDX mapping shows that dots are InGaN
- InGaN QDs are epitaxial to the underlying
- 2% InGaN underlayer + GaN cap \rightarrow PL is

$$d_{\text{gap}} = 0.95a$$

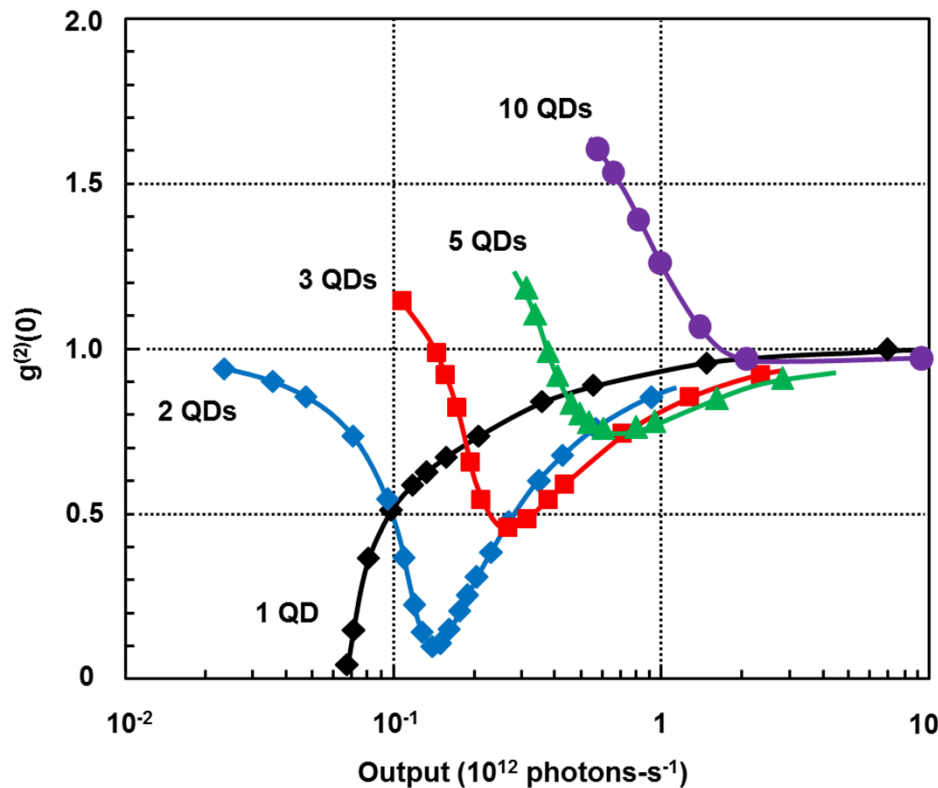


$$\begin{aligned} a &= 170 \text{ nm} \\ d &= 0.7a \\ d' &= 0.45a \\ t &= 0.5a \end{aligned}$$

$$d_{\text{gap}} = 0.6a$$



Calculated $g^{(2)}(0)$ for systems with multiple QDs

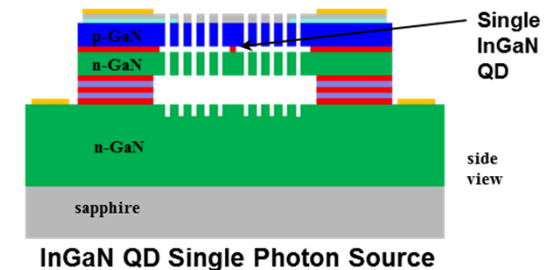
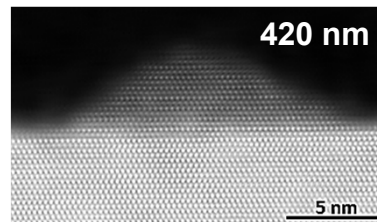
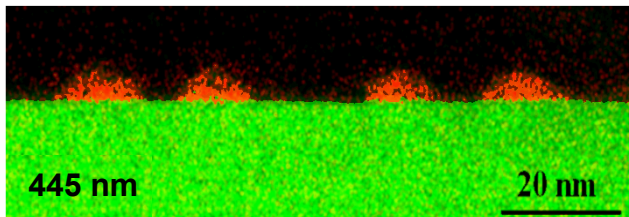
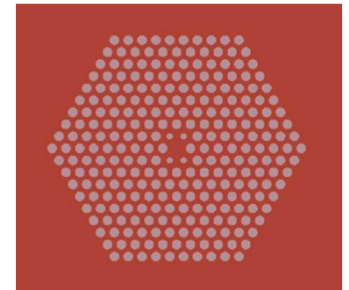
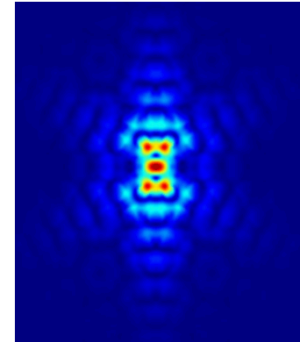


- Study the transition region between classical and quantum light sources
- Calculate g^2 using many body theory for a cavity - QD system
- Calculated for InAs QD system, but should be generally applicable
- Vary cavity Q at a constant pump rate
- Shows that we can get non-classical light for multi-QD systems
- Trade-off between low g^2 and higher photon output rate.

Details on theory: Chow, Jahnke, Gies. To appear in Light: Science and Applications

Summary/Conclusions

- **Demonstrated InGaN QDs using PEC etching**
 - TEM EDX mapping shows we have InGaN QDs
- **Quantum size-controlled etching of InGaN QDs**
 - QD size and emission λ determined by PEC wavelength
 - 40% IQE for InGaN dots emitting at 435 nm
- **Demonstrated emission from single InGaN QDs**
- **Design for PhC single photon source**
 - Deterministic placement of InGaN QDs
 - FDTD modeling of cavity resonances
- **Calculated g2 for multi-QD systems**
 - Non-classical light from multi-QD systems

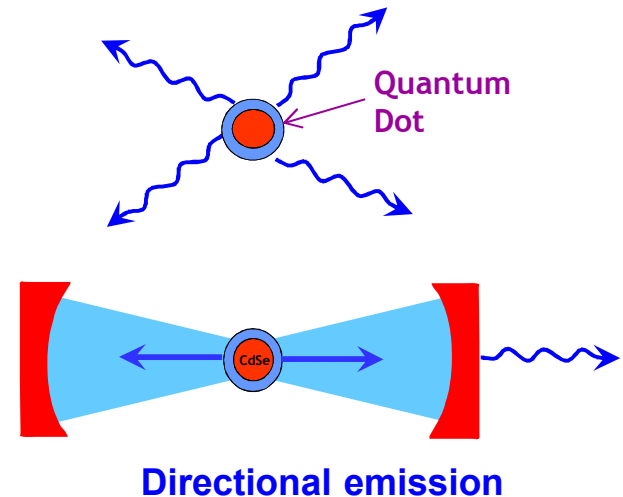


Extra slides →

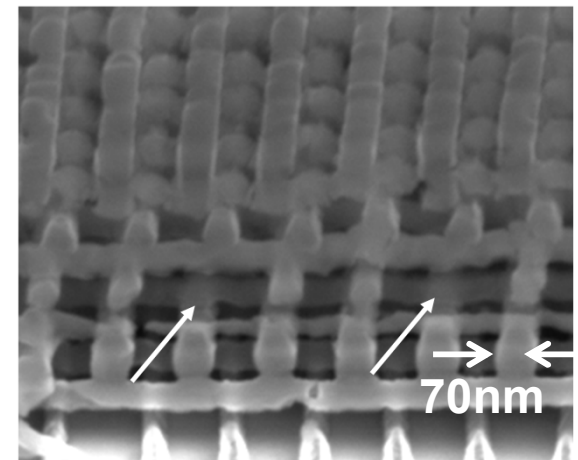
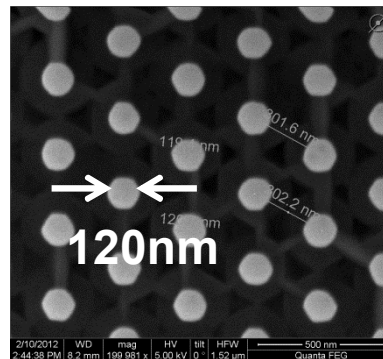
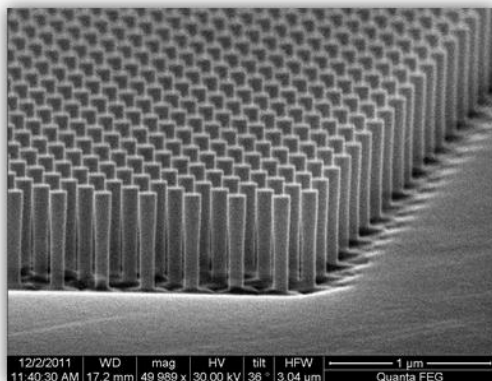
Single Emitters Inside and Optical Cavity

Why do we need an optical cavity?

- Improve photon collection efficiency
- **Restrict emission to specific spatial modes**
- Limit spectral content → indistinguishable photons
- Generate photons with a specific polarization
- Increase radiative rate, efficiency via Purcell effect
- Theoretically study QD strong coupling physics
 - Coherent and incoherent interaction with phonon bath



Sandia III-Nitride Nanostructure Fabrication



Single Photon Sources in the Literature

Faint Laser

- Not a quantum light source
- $g^{(2)}(0) = 1$

On-Demand Single Photon Sources:

- Single atoms/ions/molecules
 - $g^{(2)}(0) = 0.015$, cryogenic temperatures
- Color centers (nitrogen vacancy)
 - $g^{(2)}(0) = 0.07$, 300K
- InAs quantum dots
 - $g^{(2)}(0) = 0.02$, 5K, electrically injected
- CdSe/ZnS quantum dots
 - $g^{(2)}(0) = 0.004$, 300K, 5% extraction
- GaN-based SPSs
 - $g^{(2)}(0) = 0.16$, 10K, electrically-injected
 - $g^{(2)}(0) = 0.4$, 200K

Heralded Single Photon Sources:

- Parametric down conversion
 - $g^{(2)}(0) < 0.01$, 300K, pulsed laser
- FWM in optical fibers
 - $g^{(2)}(0) \sim 0.01$, 300K, pulsed laser

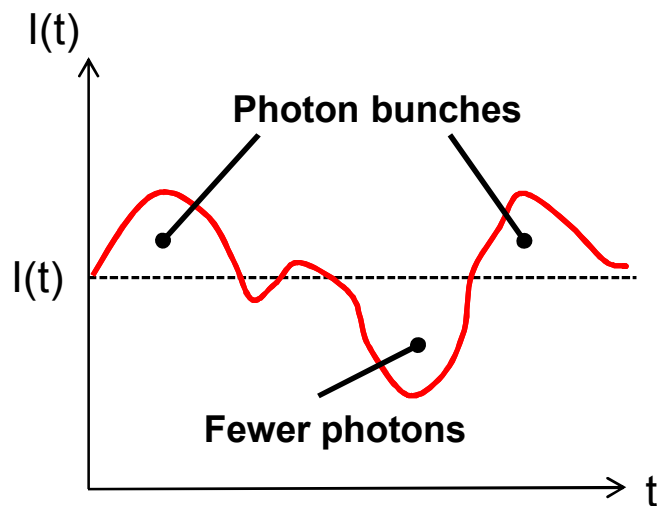
Ideal Single Photon Source:

- Triggered (on-demand)
- 100% probability of emitting one photon
- 0% probability of emitting multiple photons
- $g^{(2)}(0) = 0$
- Indistinguishable photons
- High repetition rate
- Room temperature
- Electrically injected

*M.D. Eisaman, et al. Rev. Sci. Instrum. **82**, 071101 (2011)

Single Photons for Weak absorption Measurements

- **Perfectly coherent light source has shot noise**
 - Poissonian photon statistics (random)
- **Single photon source can beat the photon shot limit**
 - Sub-Poissonian photon statistics (anti-bunched)
 - Regular emission of single photons is very low noise
- **Single photon sources deliver amplitude squeezed light**
 - Uncertainly relationship between amplitude and phase
 - Field amplitude if precisely known, but phase is unknown
- **Low noise source allows very precise absorption measurement**
 - For large transmissions and good detectors



$$St. Dev(Coherent) = \sqrt{xMT}$$

$$St. Dev(Single\ photon) = \sqrt{xMT(1 - xT)}$$

M = number of incident photons

T = transmission coefficient

x = detector QE

$$\frac{Var\ T\ (SP)}{Var\ T\ (C)} = 1 - 2x \frac{T}{1 + T}$$

Analysis from B. Lounis et al., "Single Photon Sources," Rep. Prog. Phys. **68**, 1129 (2005).

Adapted from "Quantum Optics: An Introduction" by Mark Fox

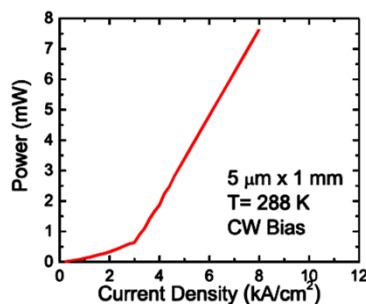
Motivation for InGaN Quantum Dot (QD) Emitters

- **Long wavelength visible emitters:**
 - Nanostructure (NWs, QDs) can incorporate more indium
 - High efficiency yellow, orange, and red emission
 - RGB and RYGB emitters require high efficiency yellow to red emitters
- **Visible QD diode lasers:**
 - Lasers for lighting is gaining momentum
 - Low threshold, high efficiency, better temperature performance
 - Monodisperse QDs

InGaN QD laser:

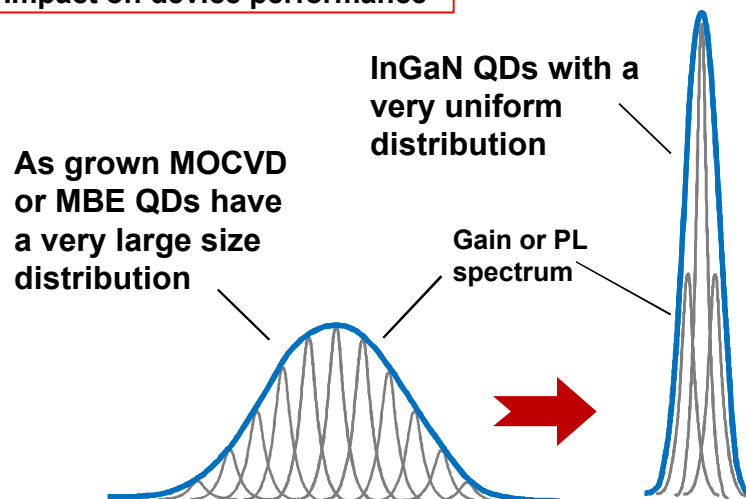
- **University of Michigan**
- Electrically injected
- 630 nm
- $T_o = 236\text{K}$

Frost et al., IEEE JQE, **49**, 923 (2013).

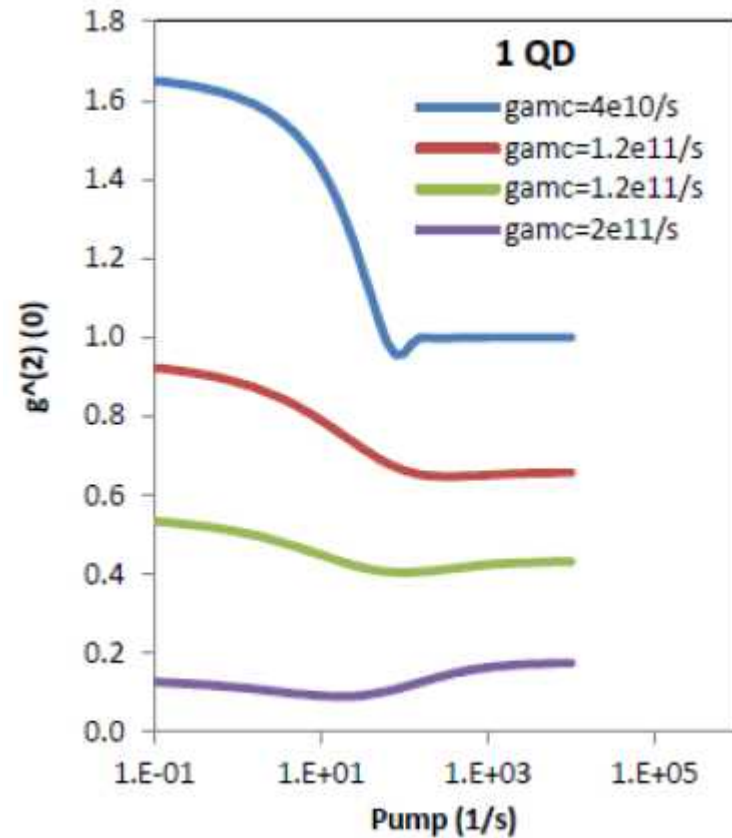
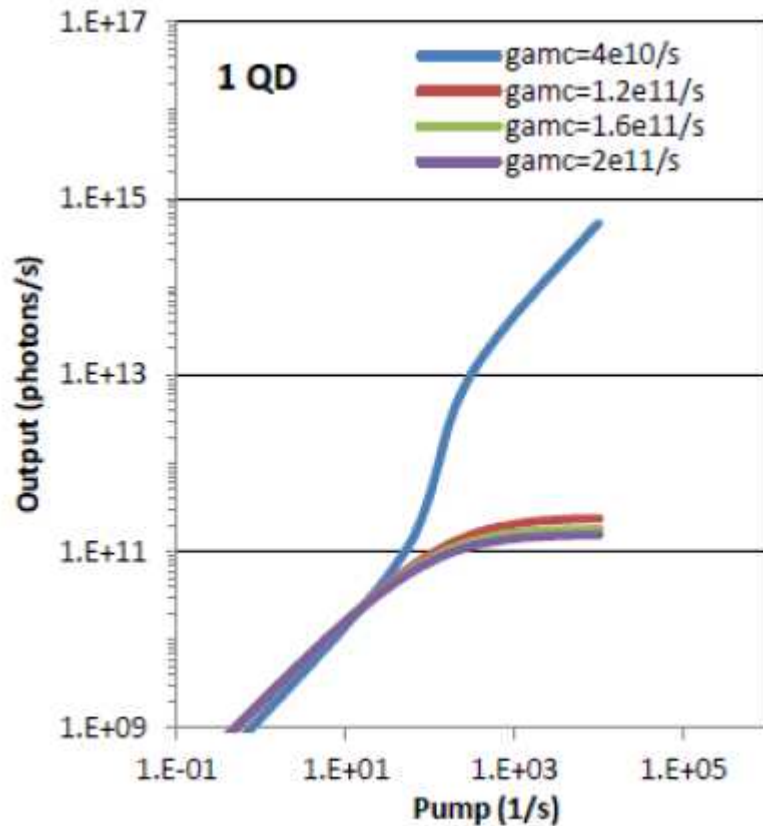


Monodisperse QD Distributions

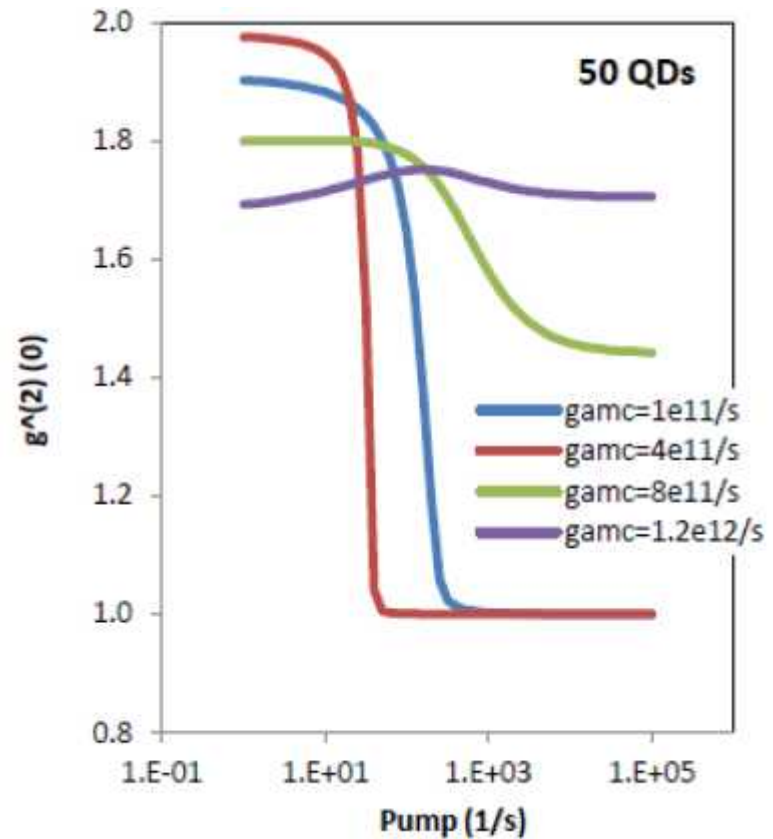
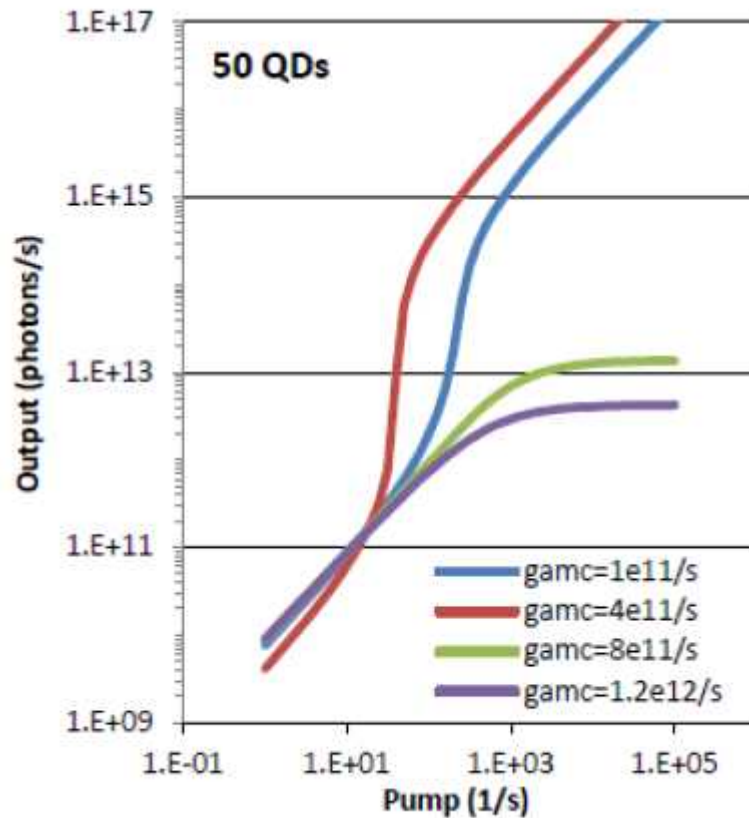
Impact on device performance



Calculated g_2 for a single QD



Calculated g_2 for 50 QDs



Calculated g_2 for 5 QDs

